FIG. 1

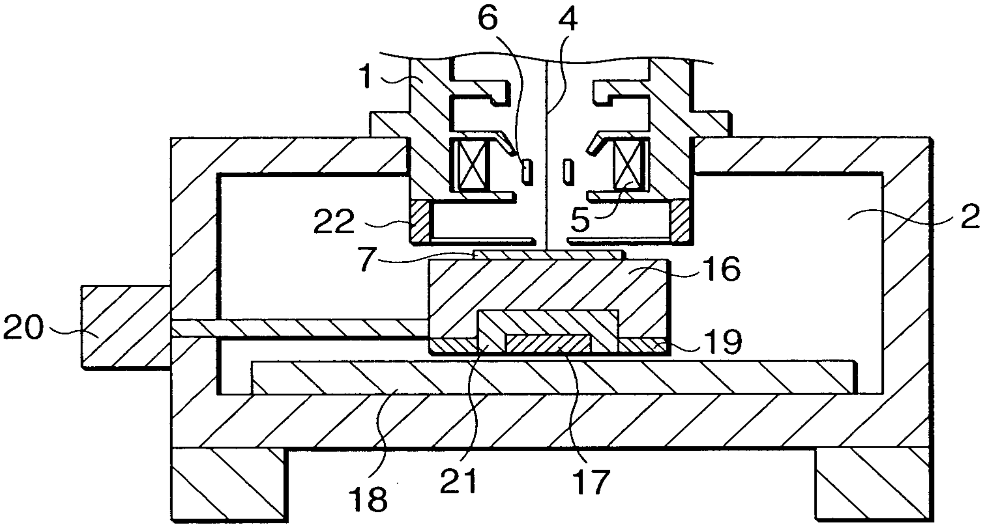
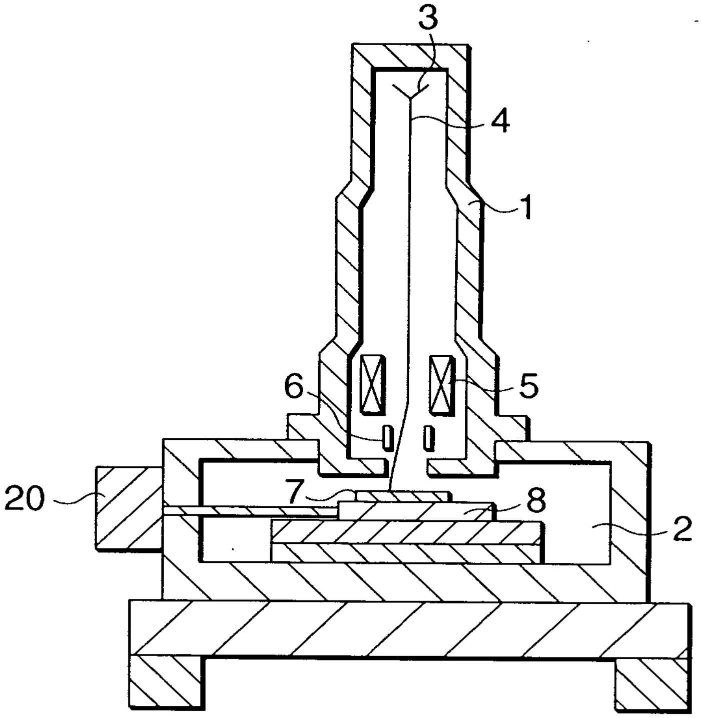
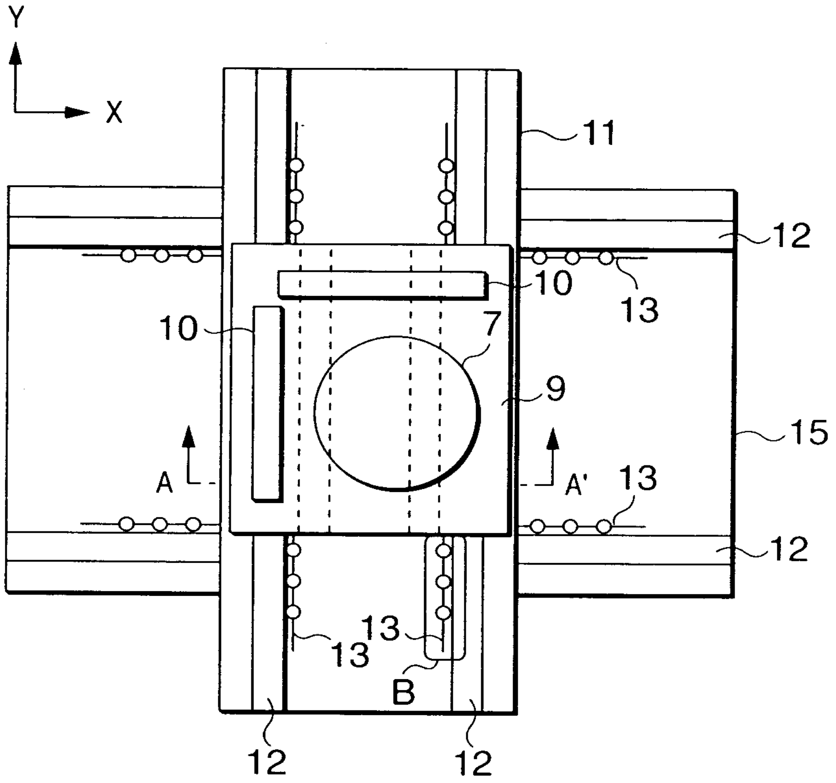


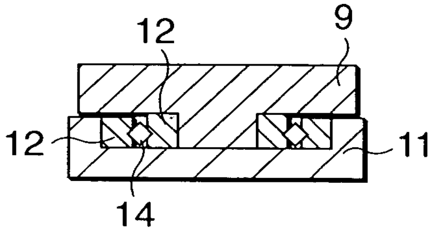
FIG. 2



F I G. 3A

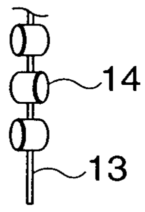


F I G. 3B



SECTIONAL VIEW TAKEN ALONG LINE A - A'

F I G. 3C



ENLARGED VIEW OF PORTION B

FIG. 4

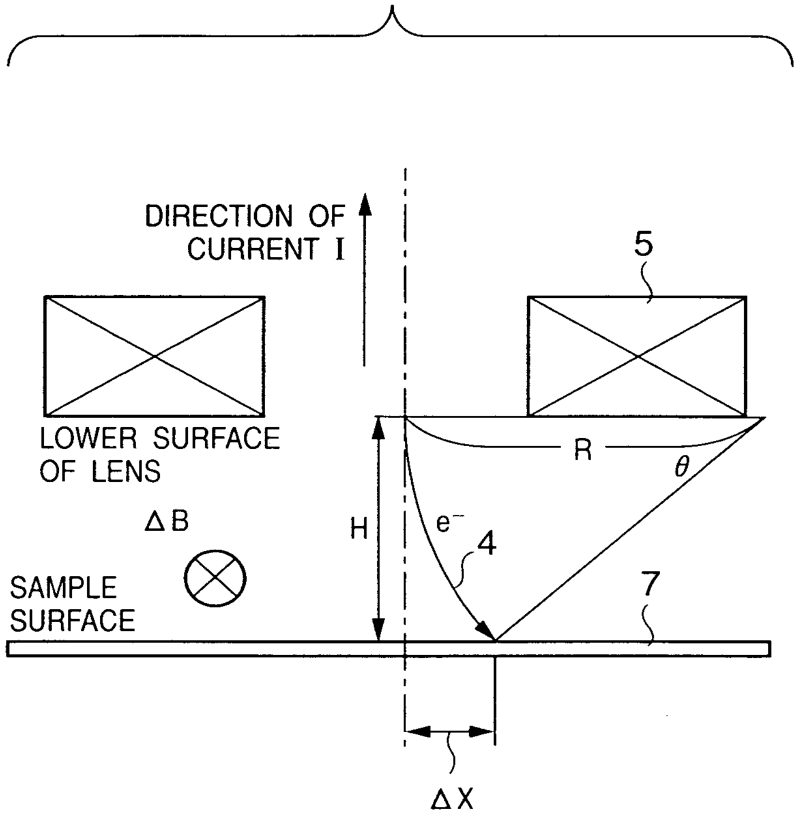
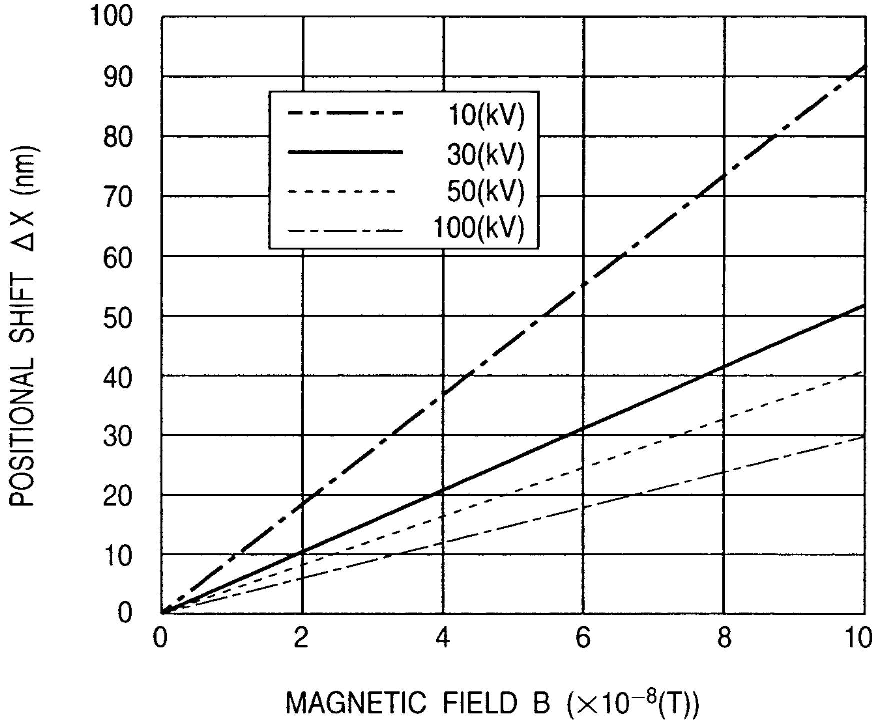

DIRECTION OF
CURRENT I
5
LOWER SURFACE
OF LENS
R
θ
ΔB
H
e⁻
4
SAMPLE
SURFACE
7
ΔX

FIG. 5



RELATIONSHIP BETWEEN POSITIONAL SHIFT OF ELECTRON BEAM AND MAGNETIC FIELD CHANGE AMOUNT (H=25(mm), E=10,30,50,100(kV))

FIG. 6A

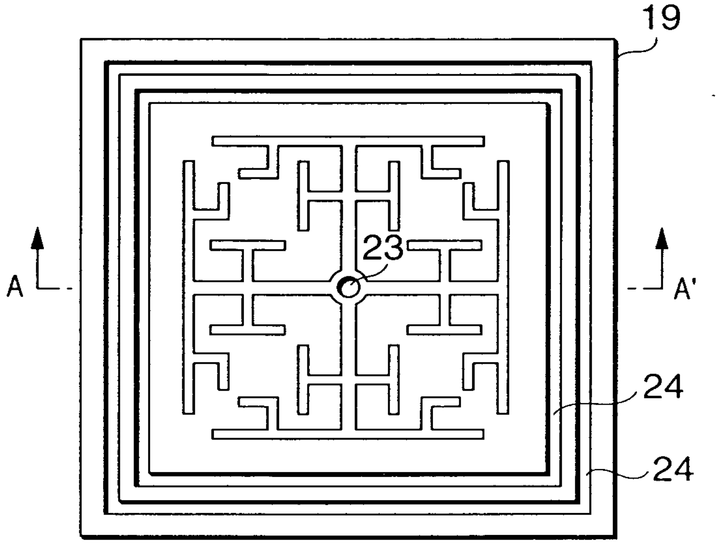
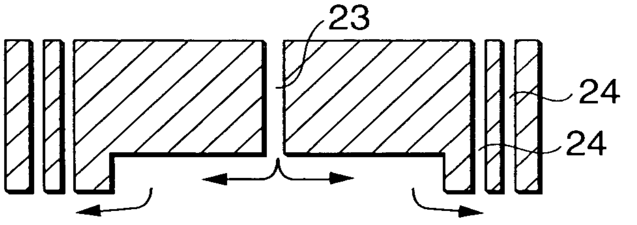


FIG. 6B



SECTIONAL VIEW TAKEN ALONG LINE A - A'

FIG. 7A

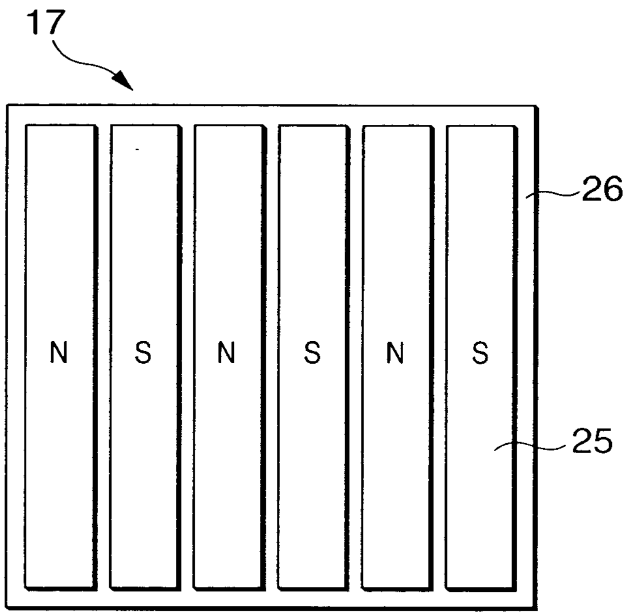


FIG. 7B

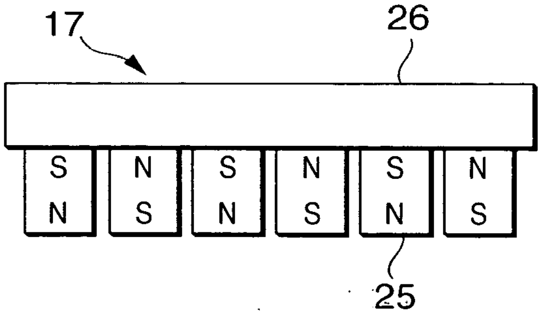


FIG. 8

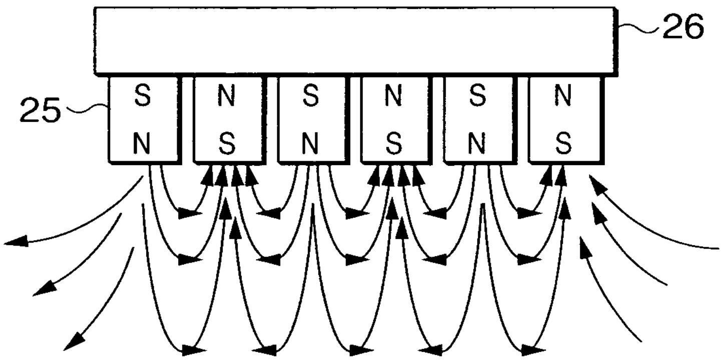


FIG. 9

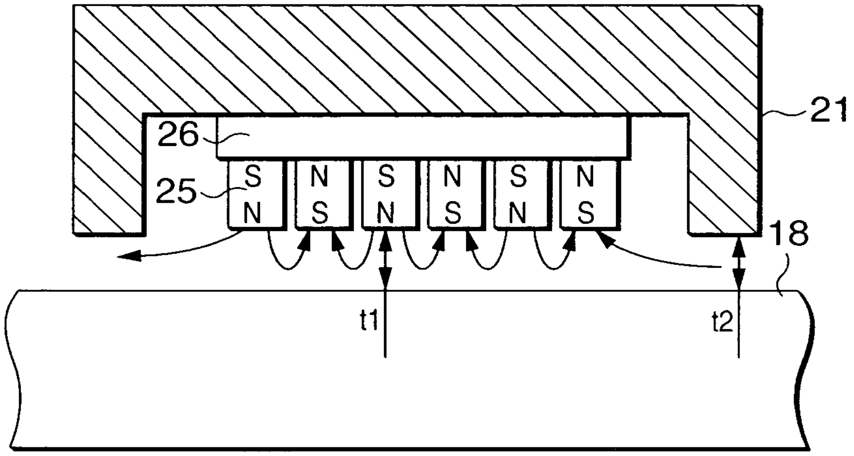
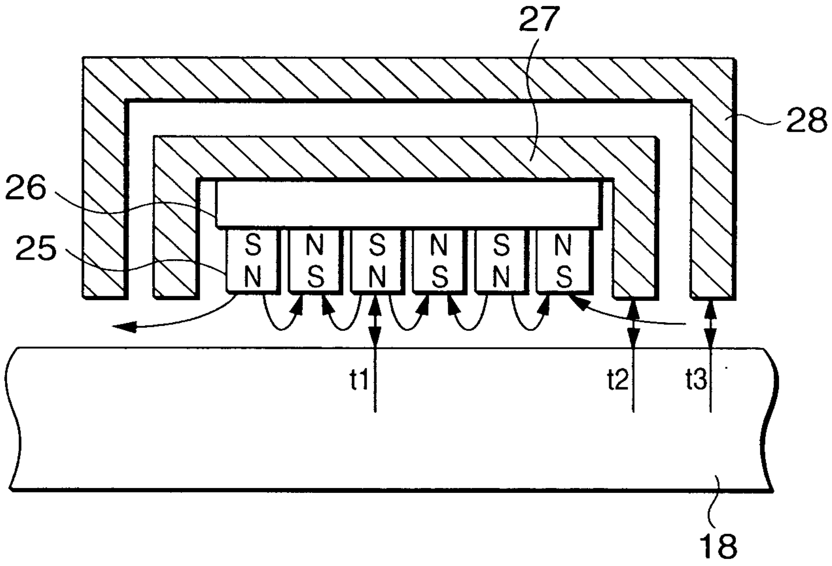
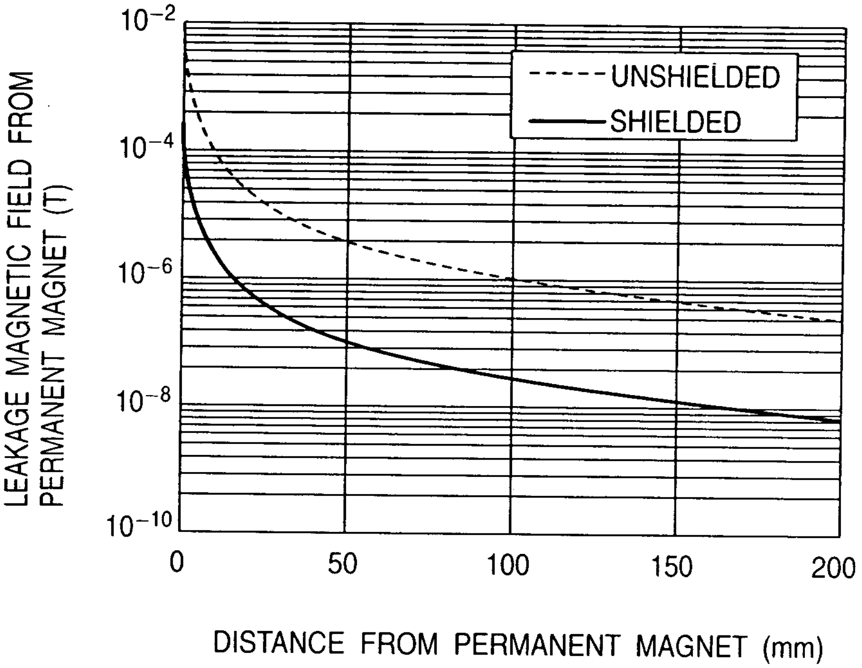


FIG. 10



F I G. 11



EXTERNAL MAGNETIC FIELD SHIELD EFFECT OF PERMANENT MAGNET

FIG. 12

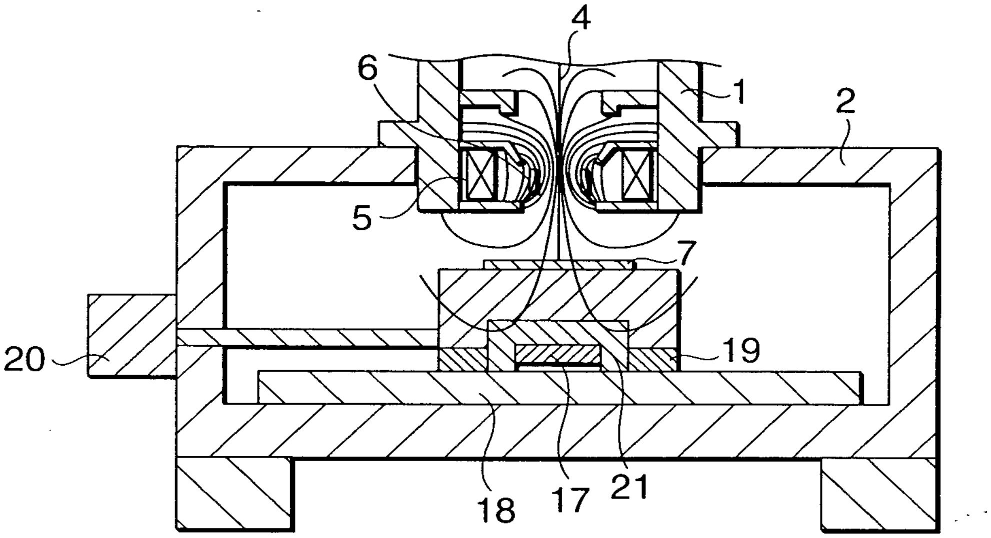


FIG. 13

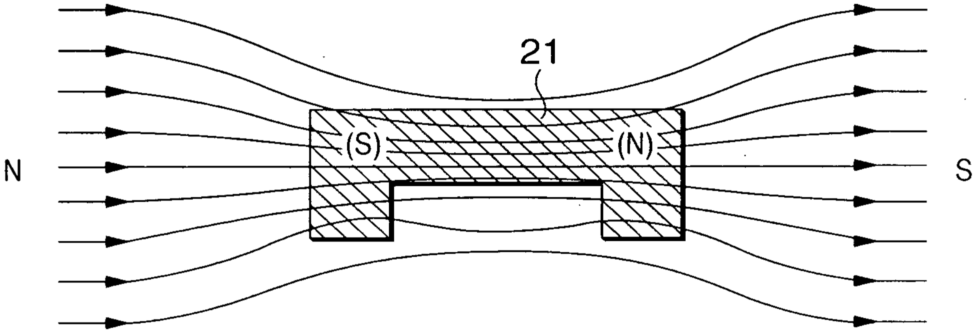
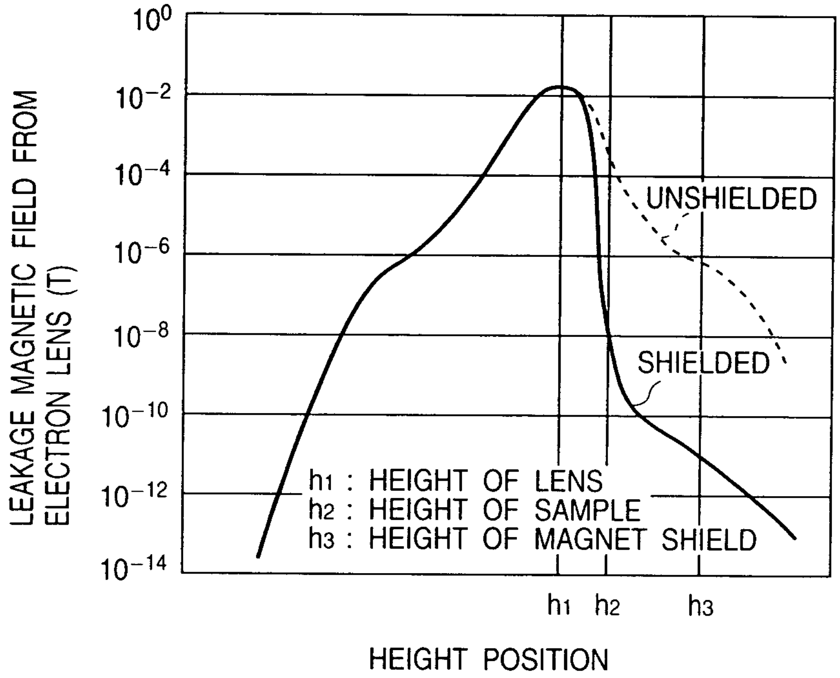
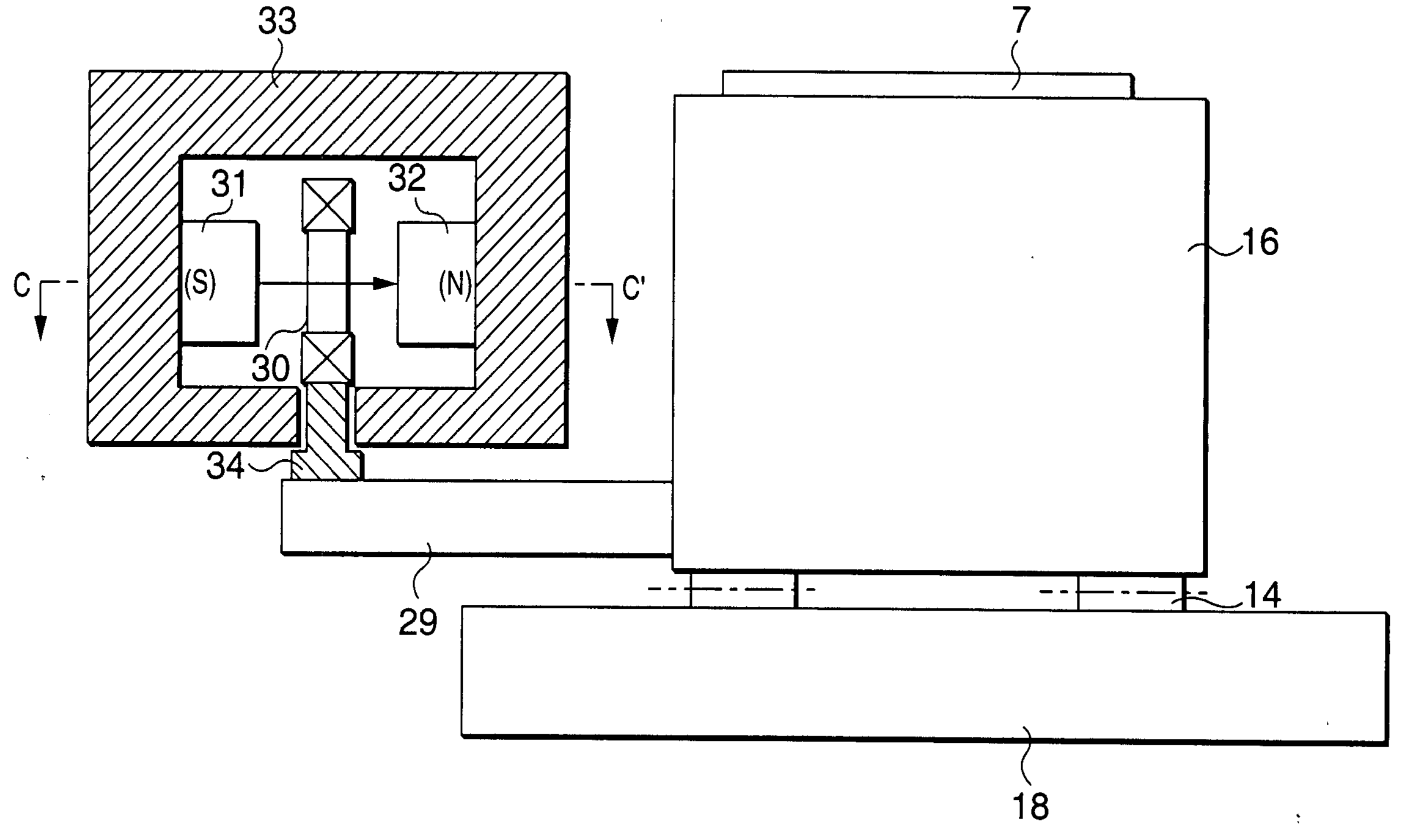


FIG. 14

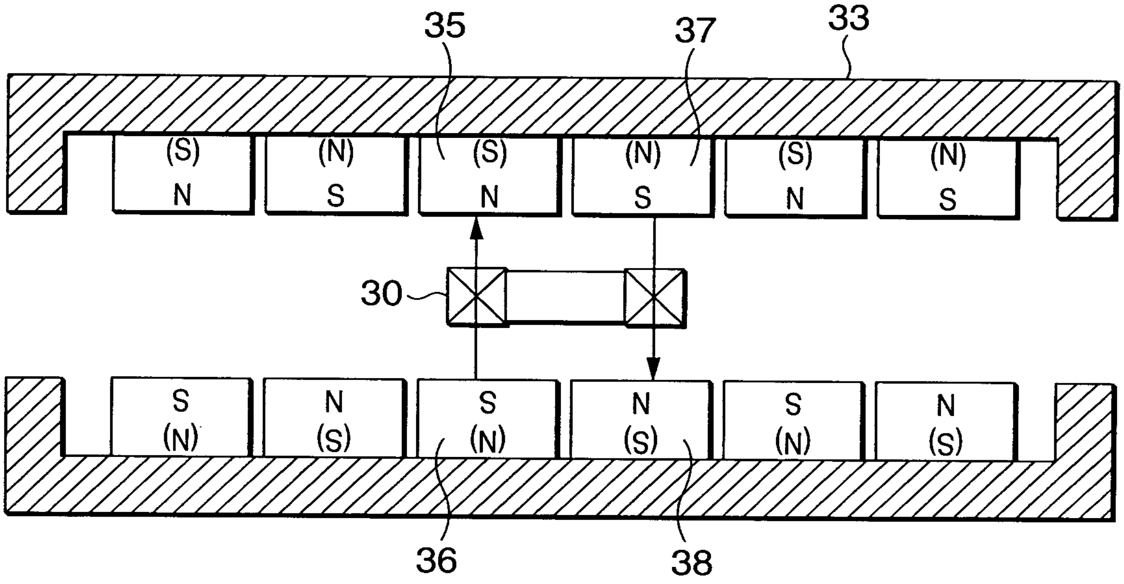


SHIELD EFFECT FOR ELECTRON LENS LEAKAGE MAGNETIC FIELD

FIG. 15

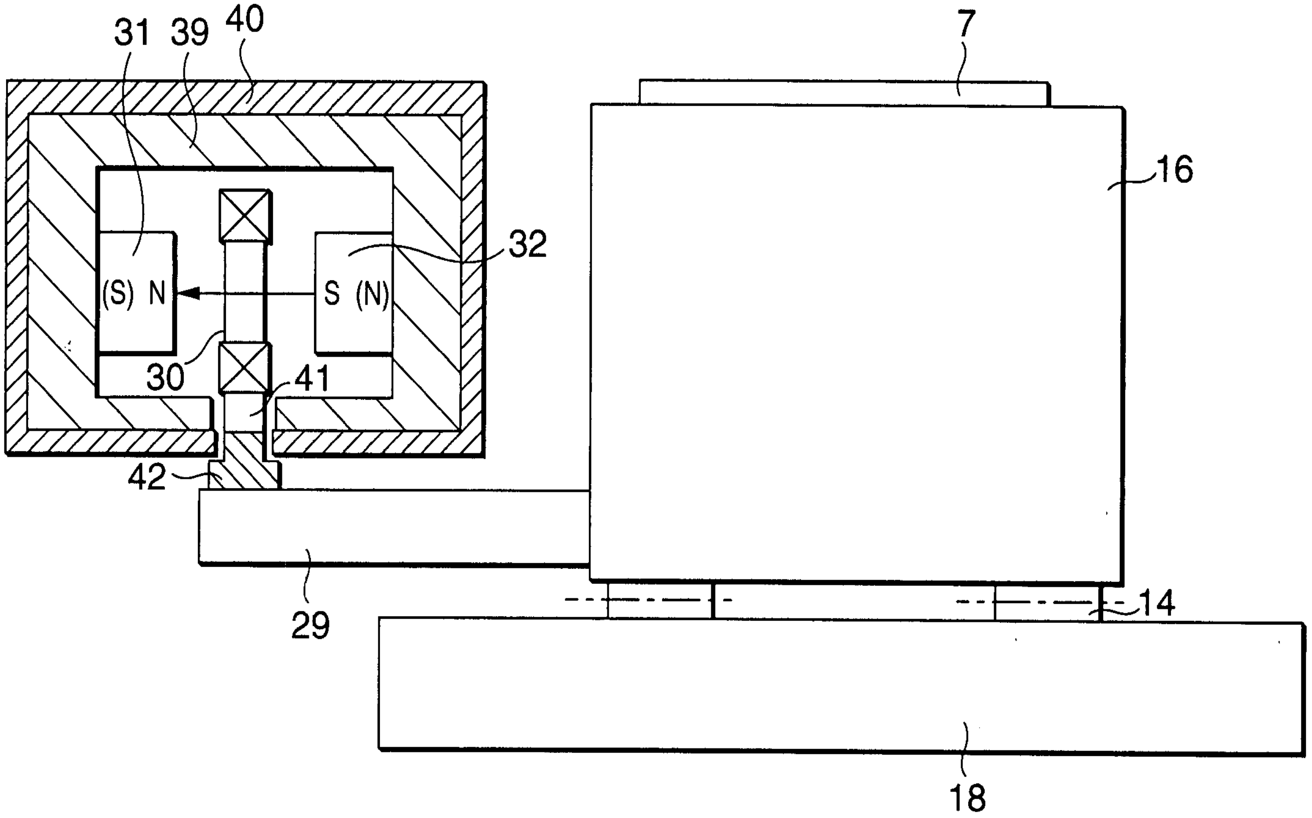


F I G. 16



CROSS-SECTIONAL VIEW TAKEN ALONG LINE C - C'

FIG. 17



F I G. 18

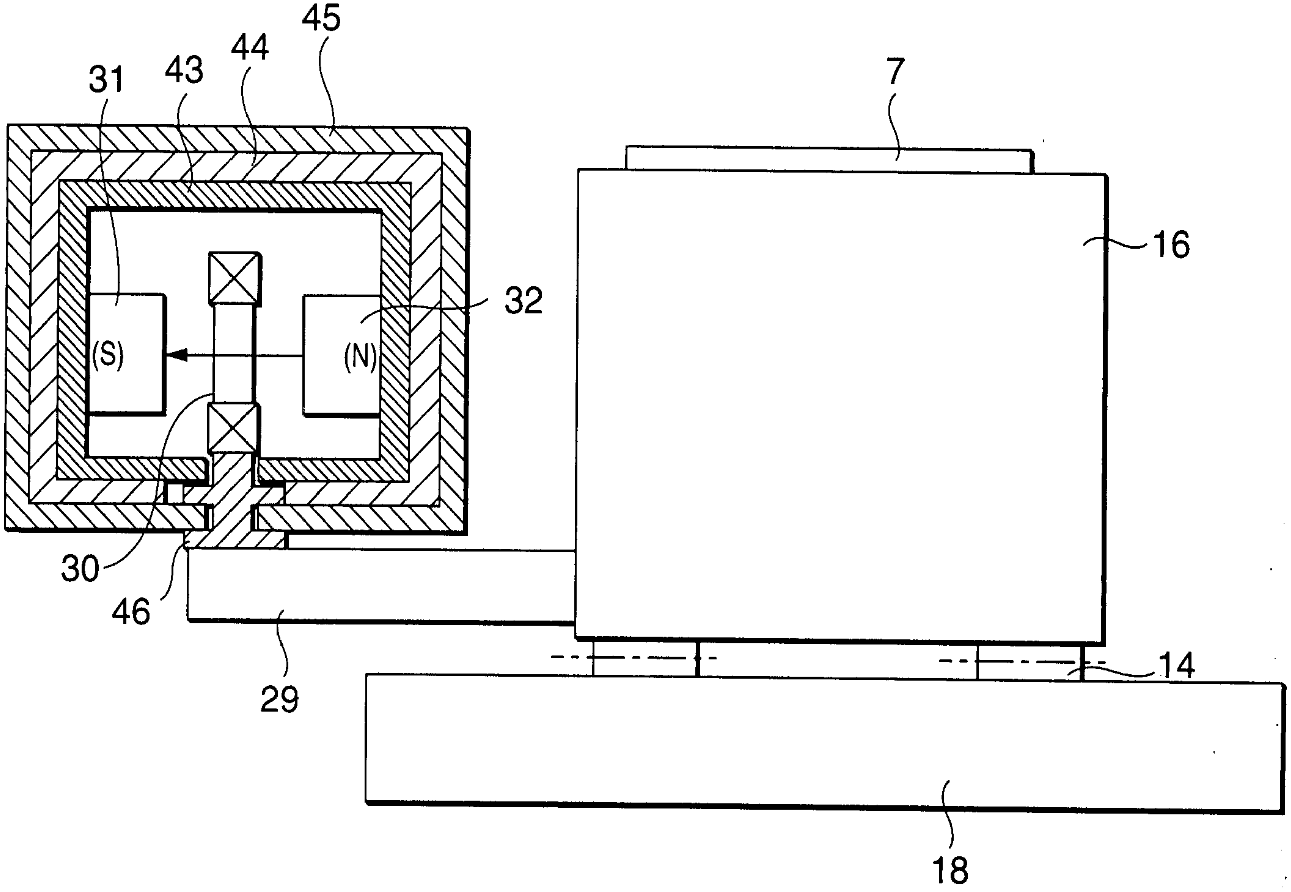


FIG. 19

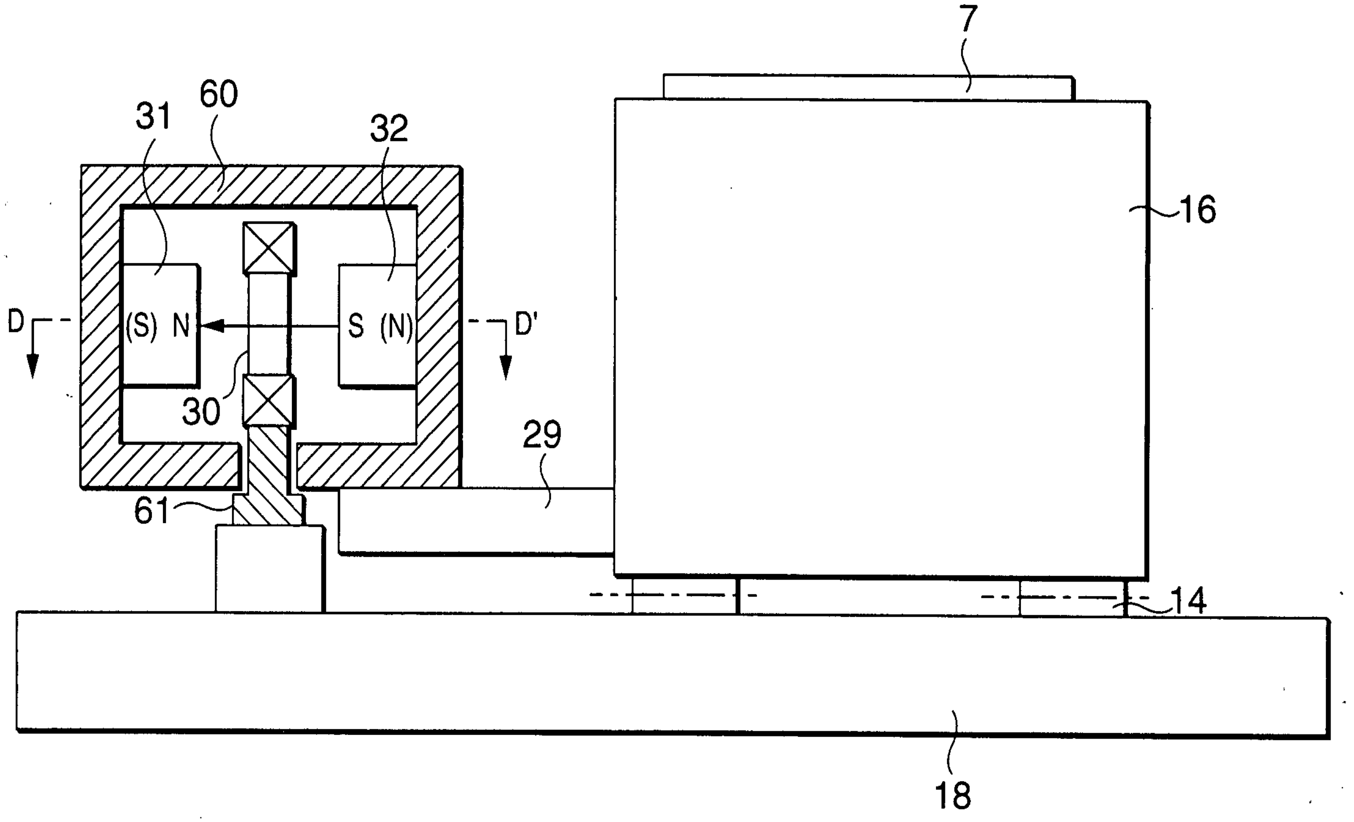
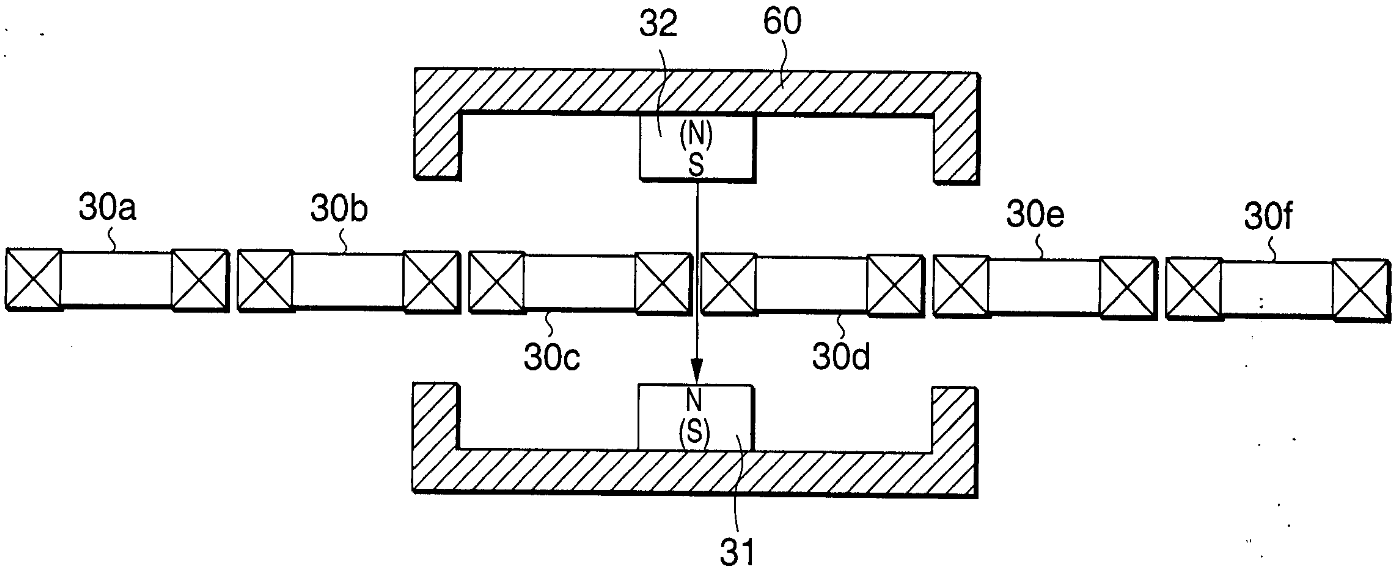
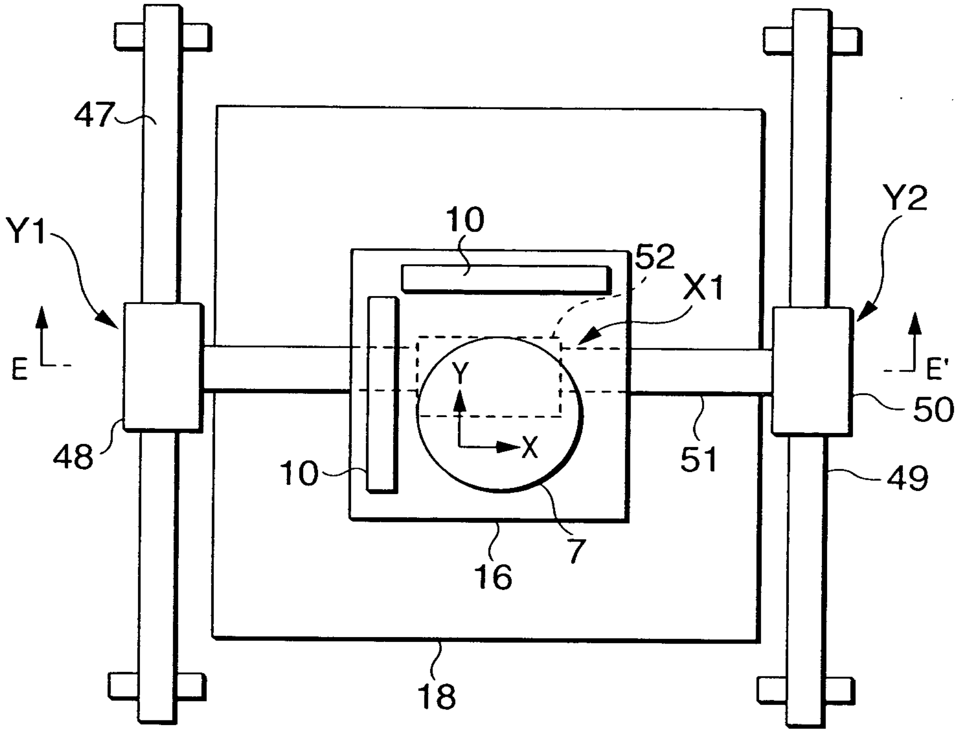


FIG. 20

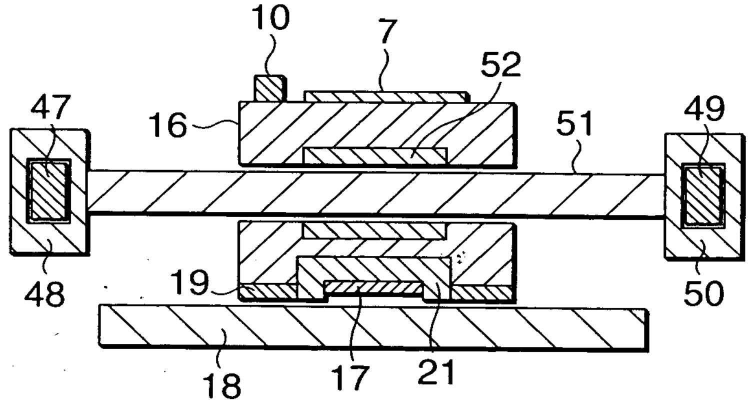


CROSS-SECTIONAL VIEW TAKEN ALONG LINE D - D'

F I G. 21A



F I G. 21B



SECTIONAL VIEW TAKEN ALONG LINE E - E'

F I G. 22

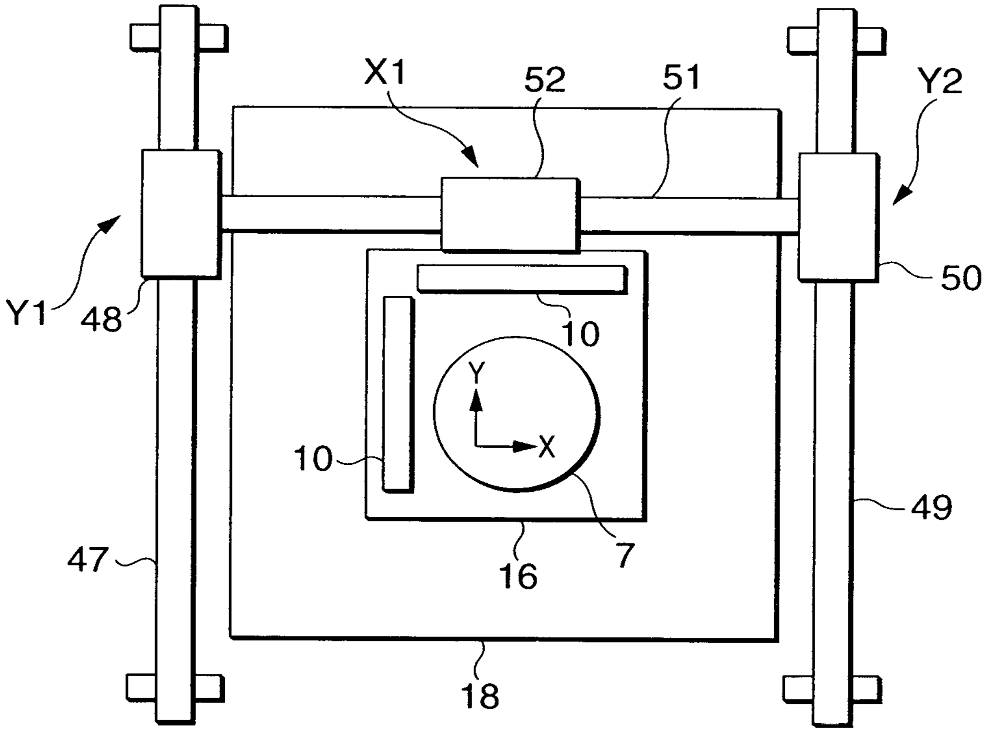


FIG. 23

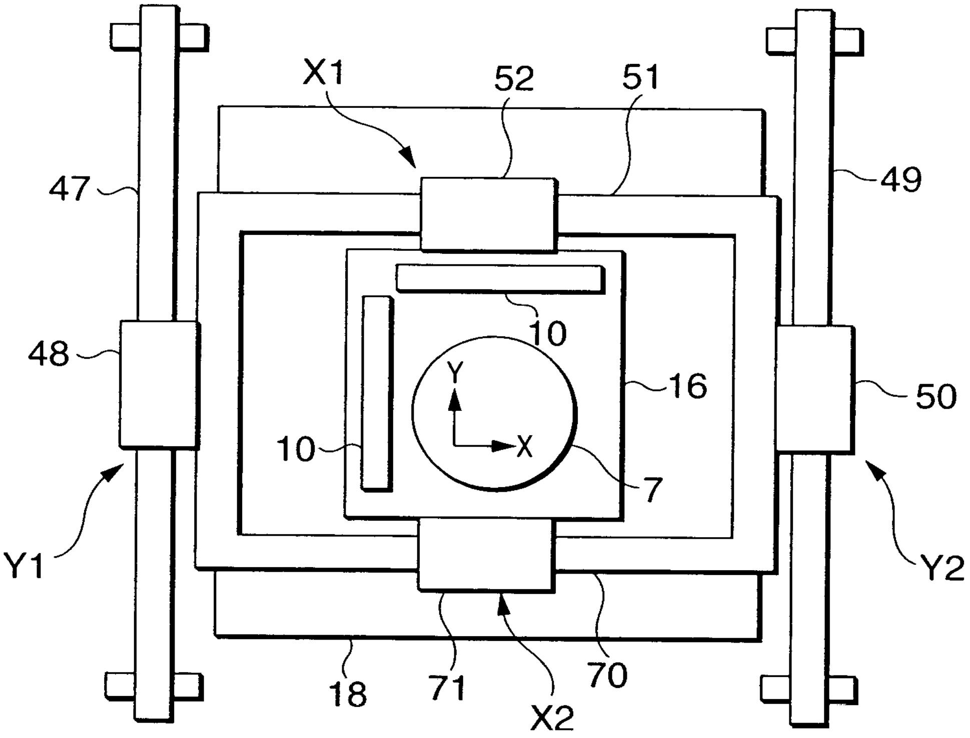


FIG. 24A

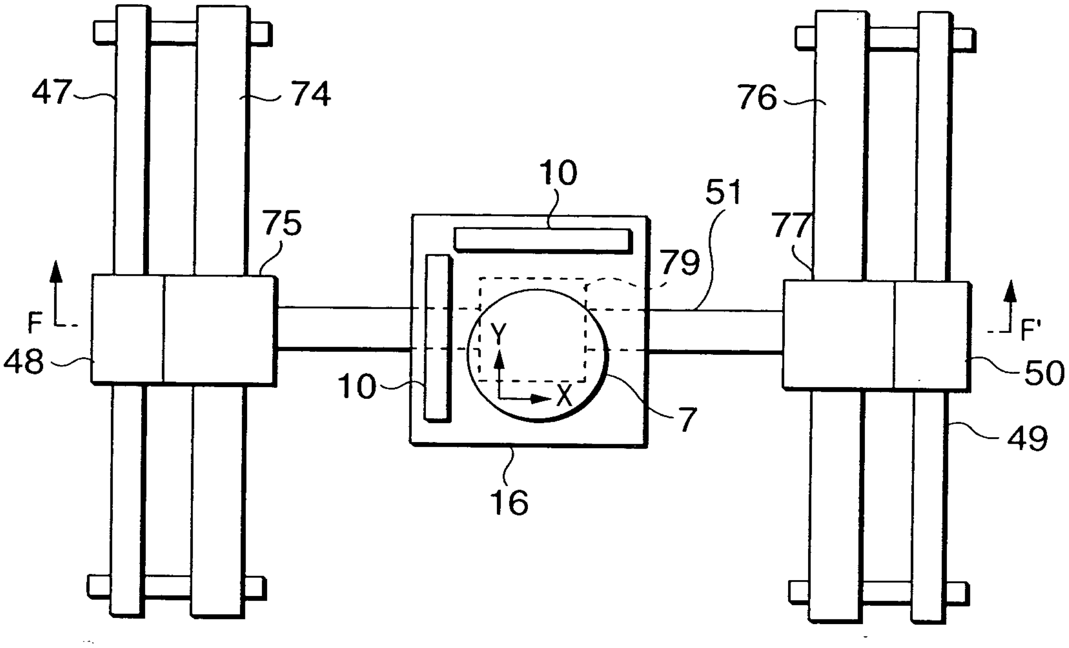
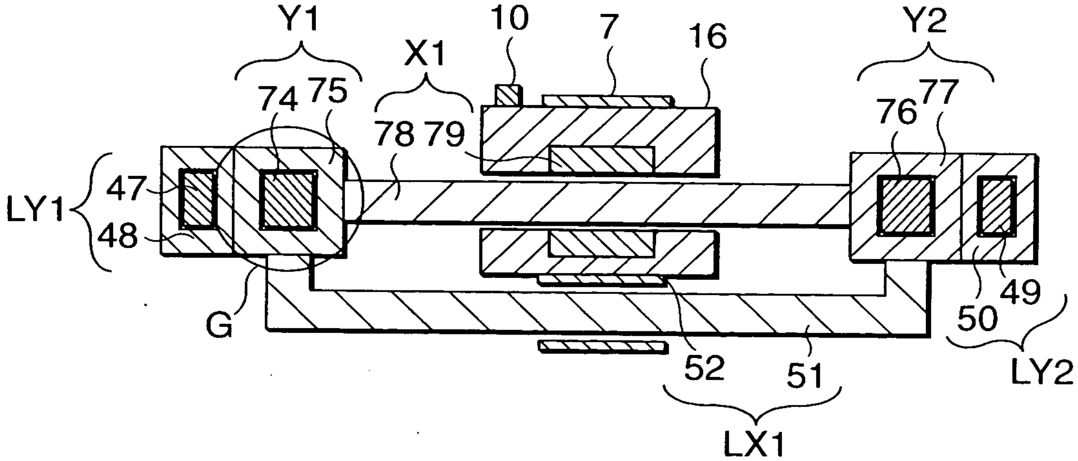
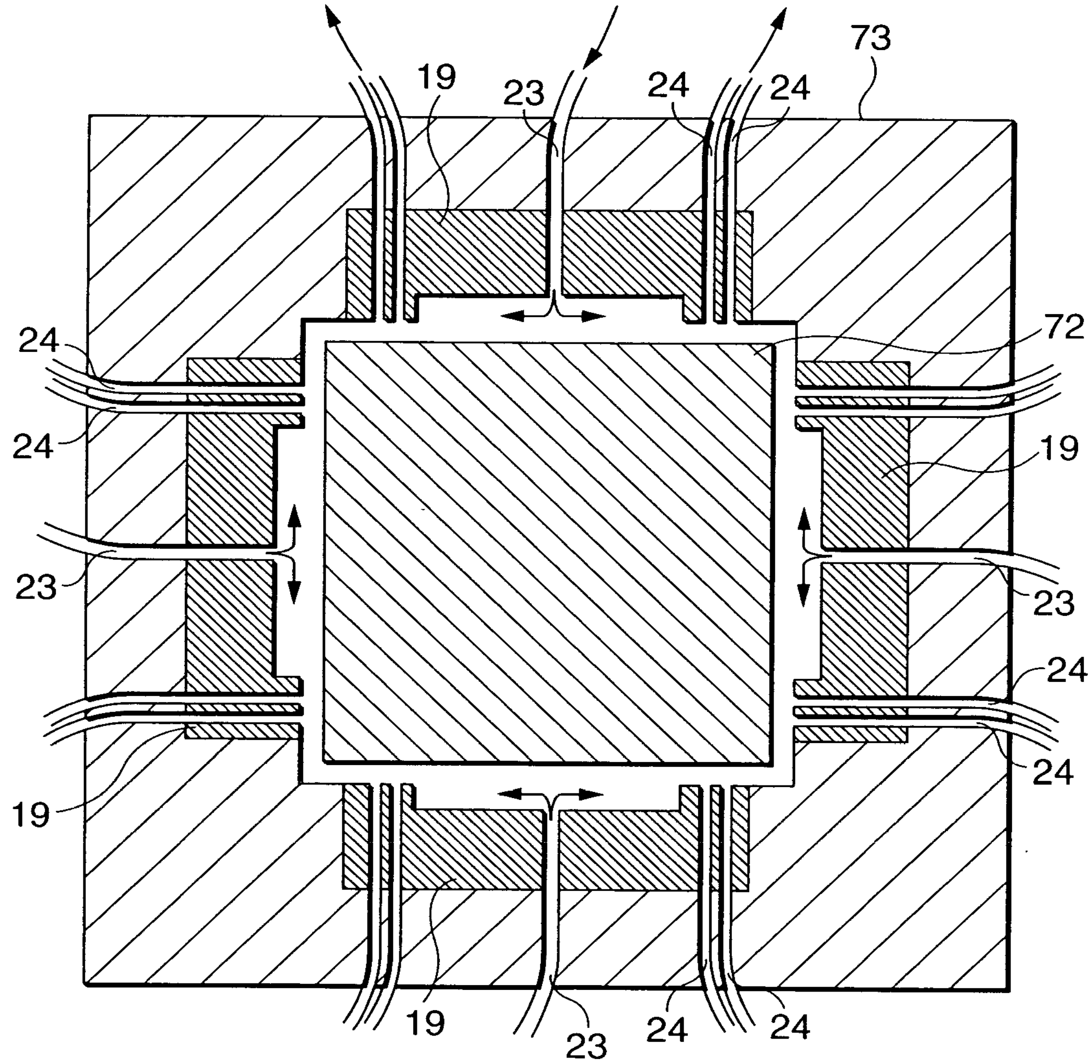


FIG. 24B



SECTIONAL VIEW TAKEN ALONG LINE F - F'

FIG. 25



ENLARGED VIEW OF PORTION G IN FIG.24B

FIG. 26A

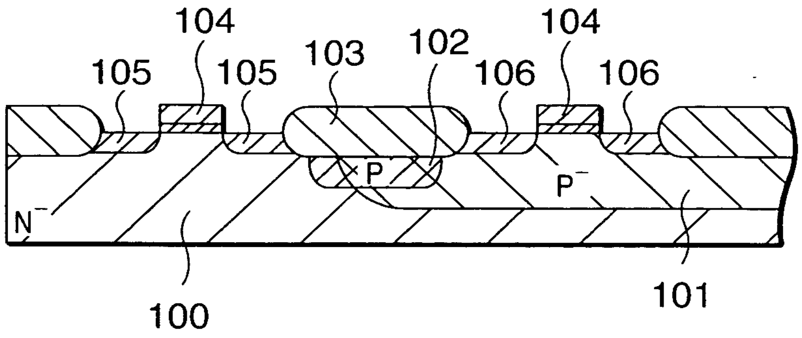


FIG. 26B

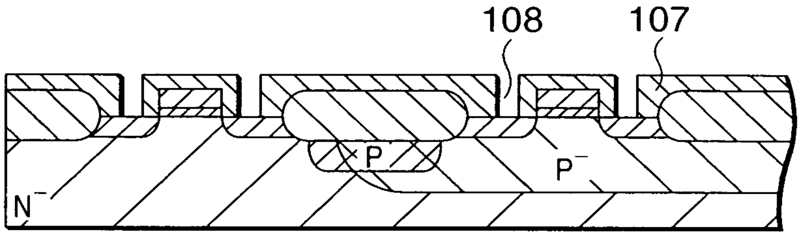


FIG. 26C

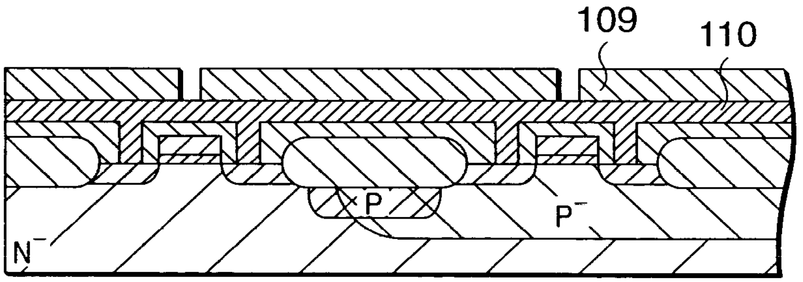


FIG. 26D